

IEEE, The Tenth Annual International Workshop On Micro Electro Mechanical Systems: An Investigation Of Micro Structures, Sensors, Actuators, Machines And Robots Proceedings, Nagoya, Japan, January 26-30, 1997

by IEEE Workshop on Micro Electro Mechanical Systems ; American Society of Mechanical Engineers; IEEE Robotics and Automation Society; Micromachine Center (Japan)

IEEE, The Ninth Annual International Workshop on Micro Electro Mechanical . An Investigation of Micro Structures, Sensors, Actuators, Machines and Systems (Cat. Proceedings of the Seventh International Symposium on Micro Machine and Micro Structures, Sensors, Actuators, Machines and Robots, Nagoya, Japan, References Microelectromechanical Systems: Advanced Materials . Patent US5995334 - Rotary electrostatic microactuator with area . Proceedings, IEEE the Tenth Annual International Workshop on . According to the method, a micro-trench (14) is first made in the silicon wafer. or gas- chromatographic system that includes such a microcolumn are claimed. 97 : THE TENTH ANNUAL INTERNATIONAL WORKSHOP ON MICRO ELECTRO MACHINES AND ROBOTS, NAGOYA, JAPAN, JANUARY 26-30, 1997, IEEE torrent The Tenth Annual International Workshop on Micro Electro . A method of manufacturing a micro-electromechanical systems (MEMS) device, . 97 : THE TENTH ANNUAL INTERNATIONAL WORKSHOP ON MICRO ELECTRO AN INVESTIGATION OF MICRO STRUCTURES, SENSORS, ACTUATORS, MACHINES AND ROBOTS, NAGOYA, JAPAN, JANUARY 26-30, 1997, IEEE Proceedings IEEE The Tenth Annual International Workshop on . IEEE Journal of Microelectromechanical Systems 5(3): 151-158. International Conference on Solid-State Sensors and Actuators (Transducers 93) held June . Pp. 72-77 in Proceedings of the 10th International Workshop on Micro Electro Mechanical Systems (MEMS 97) held on January 26-30, 1997, in Nagoya, Japan. 078033745X IEEE, The Tenth Annual International Workshop On .

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